

(Use several sheets if necessary.)

09/903,764

2823

JUL 24 2001

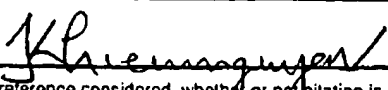
PATENT DOCUMENTS

[illegible][illegible]

T. DANU

10/9/02

SHEET 1 OF 1

<div style="display: flex; align-items: center;"> <div style="border: 1px solid black; border-radius: 50%; padding: 5px; margin-right: 10px; text-align: center;"> INFORMATION DISCLOSURE CITATION <small>(Use several sheets if necessary)</small> SEP 03 2003 348 </div> <div> INFORMATION DISCLOSURE CITATION <small>(Use several sheets if necessary)</small> </div> </div>				ATTY DOCKET NO. OKA-C104		SERIAL NO. 09/903,764									
				OKU et al		FILING 07/13/2001		GROUP 2823							
U.S. PATENT DOCUMENTS															
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE									
K.N.	4,282,268	8/4/81	PRIESTLEY et al	427	39										
/															
FOREIGN PATENT DOCUMENTS															
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION									
						YES	NO								
K.N.	0 664 560 A2	18/01/95	EP												
/															
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)															
K.N.		Vestiel et al, "A Low Dielectric Film Obtained by Polymerization of..."; 30th European Microwave Conf. Proceed., Paris, Oct. 3-5, 2000, Vol., 3 of 3, Conf. 30, 5 Oct 2000 pgs 233-236													
K.N.		Bogart et al, "Deposition of SiO2 Films from Novel Alkoxysilane/O2 Plasmas", Jorنال of Vacuum Science and Technology, Part A, American Institute of Physics, Vol. 16, No. 6, November 1998 (1998-11), Pages 3175-3184													
EXAMINER				DATE CONSIDERED											
				12/19/03											
EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.															

PAGE 1 OF 1

APR. 20 2004
PATENT & TRADEMARK OFFICE
JCI74

2823

[illegible][illegible]

Kriemhilden

05/03/04

SHEET 1 OF 1